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SERIAL NUMBI 10/612,074			CLASS 438		GROUP ART UNIT		ATTORNEY DOCKET NO. P68962US0		
APPLICANTS Jae Han Cha, Cheongjoo-Shi, KOREA, REPUBLIC OF;									
CONTINUING DATA									
** FOREIGN APPLICATIONS ************************************									
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 09/29/2003									
Foreign Priority claimed 35 USC 119 (a-d) cond met Verified and Acknowledged	itions	HINIVXX XXXXX	tials	STATE OR COUNTRY KOREA, REPUBLIC OF	DRA	ETS WING 2	TOT CLAI 15	MS	INDEPENDENT CLAIMS 2
ADDRESS 00136 JACOBSON HOLMAN PLLC 400 SEVENTH STREET N.W. SUITE 600 WASHINGTON , DC 20004									
TITLE Method of forming an isolation film in a semiconductor device									
FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNT No for following: All Fees 1.16 Fees (Filing) 1.17 Fees (Processing Ext. of time)									